

## Claims

1. A quantity-of-light unevenness inspection apparatus, comprising:

photographing means for photographing an opening from a side across a light source when the light from the light source is applied to the opening in a given shape for adjusting light so that a film is irradiated with the light;

luminance signal detecting means for detecting a luminance signal of the opening based on the image of said opening shot by said photographing means;

luminance level waveform pattern creating means for creating a luminance level waveform pattern according to said luminance signal; and

display means for displaying said luminance level waveform pattern as quantity-of-light unevenness of said light with which said opening is irradiated.

2. The quantity-of-light unevenness inspection apparatus according to Claim 1, wherein

said luminance signal detecting means detects a luminance signal for one line at a specified measurement position of said opening based on the image of said opening.

3. The quantity-of-light unevenness inspection apparatus

according to Claim 2, wherein

said luminance signal detecting means detects luminance signals for one line at a new measurement position changed by a user with a switching means.

4. The quantity-of-light unevenness inspection apparatus according to Claim 1, wherein

said luminance signal detecting means detects the integral value of the luminance in a fixed detection region in the opening as said luminance signal based on the image of said opening.

5. The quantity-of-light unevenness inspection apparatus according to Claim 4, wherein

said luminance signal detecting means detects the integral value of the luminance in a new detection region changed by a user with a switching means.

6. The quantity-of-light unevenness inspection apparatus according to Claim 1, wherein

said display means overlaps and displays the image of said opening shot by said photographing means and said luminance level waveform pattern.

7. The quantity-of-light unevenness inspection apparatus according to Claim 1, wherein

said display means displays a normalized scale in which a luminance level indicated in the form of said luminance level waveform pattern is relatively and digitized, in correspondence with said luminance level waveform pattern.

8. A quantity-of-light unevenness inspection method, comprising:

a photographing step of photographing an opening from a side across a light source when said opening in a given shape for adjusting light so that a film is irradiated with the light, is irradiated with the light;

a luminance signal creating step of creating a luminance signals of the opening based on the image of said opening photographed from said photographing means;

a luminance level waveform pattern creating step of creating a luminance level waveform pattern according to said luminance signal; and

a display step of displaying said luminance level waveform pattern as quantity-of-light unevenness of said light with which said opening is irradiated.

9. The quantity-of-light unevenness inspection method according to Claim 8, wherein

said luminance signal detecting step detects a luminance signal for one line at a specified metering position of said

opening based on the image of said opening.

10. The quantity-of-light unevenness inspection method according to Claim 9, wherein

said luminance signal detecting step detects a luminance signal for one line at a new metering position changed by a user with a switching means.

11. The quantity-of-light unevenness inspection method according to Claim 8, wherein

said luminance signal detecting step detects the integral value of the luminance in a fixed detection region in the opening as said luminance signal based on the image of said opening.

12. The quantity-of-light unevenness inspection method according to Claim 11, wherein

said luminance signal detecting step detects the integral value of the luminance in a new detection region changed by a user with a switching means as said luminance signal.

13. The quantity-of-light unevenness inspection method according to Claim 8, wherein

said display step overlaps and displays the image of said opening shot by said photographing means and said luminance level waveform pattern.

14. The quantity-of-light unevenness inspection method according to Claim 8, wherein

said display step displays a normalized scale in which a luminance level indicated in the form of said luminance level waveform pattern is relatively digitized, in correspondence with said luminance level waveform pattern.